

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: OKUBO et al.

Application No.: 10/544,178

Confirmation No.: 8571

Filed: August 1, 2005

Group Art Unit: Unknown

Examiner: Unknown

Title: INSPECTION METHOD, MANUFACTURING METHOD OF PIECE FOR ANALYSIS, ANALYSIS METHOD, ANALYZER, MANUFACTURING METHOD OF SOI WAFER, AND SOI WAFER

April 24, 2006

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SECOND PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Prior to the examination of this application on its merits, please enter the following amendments and consider the following remarks: